

MICROTEST

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Quickstep Lift-Off System

The Lift-Off System is a low cost semi-automated solution for metal lift off applications. It provides repeatable process control from wafer to wafer. Equipped with a programmable dispense arm several types of lift off methods are possible. The dispense arm can be equipped with spray, puddle or high-pressure nozzle options for various lift off techniques. These applications requiring heated chemicals can also be configured on the System. The main benefit to our customer is the repeatable process control and higher yield realized by eliminating human inconsistencies. Additionally, the system can be configured to run the production proven processes that are available on our fully automated microcluster Lift off System. It's a versatile tool that can also process pieces from broken or damaged wafers. Manual loading and unloading of the substrates is very easy due to the unrestricted access of the process chamber. For safety purposes an integrated and interlocked automatic process chamber door containing a safety interrupt sensor is standard.

The Lift-Off System can be configured to process wafers up to 12" Ø (300 mm) or substrates up to 9" x 9" (230 x 230 mm). The stainless steel cabinet and all parts, which are in contact with process chemicals, are made of fire resistant materials. Process programming is very user friendly. The standard controller can hold unlimited recipes. The optional laptop accessory can provide unlimited recipe storage

Features

- Wafer size: up to Ø 12" (300 mm)
- Substrate size: up to 9" x 9" (230 x 230 mm)
- Unlimited recipes are programmable
- Programmable acceleration and deceleration ramp
- Programmable spin speed from 1 up to 4.000 U/min
- Diagnostic system with clear text



System Configuration

- ◆ Brushless servomotor with resolver, Spin speed up to 4.000 rpm AC Servo controller
- ◆ Process chamber with safety door
- ◆ Built in digital controller allows choice of linear acceleration- or \sin^2 ramp.
- ◆ Recipe programming
- ◆ All process parameters can be password protected.
- ◆ A recipe library of unlimited recipes
- ◆ Acceleration- and deceleration ramps are programmable.
- ◆ Diagnostic system is provided with clear text
- ◆ Up to 8 programmable outputs for customized options.
- ◆ Waste collection system is included with connection for external exhaust controlled by manually adjustable throttle valve.
- ◆ A programmable arm with up to 4 dispense positions for spray, puddle or high-pressure applications.

Facilities

- ◆ Foot print 1200 x 800 x 1400 mm
- ◆ Nitrogen: 6mm tubing
- ◆ DI water: 8mm tubing
- ◆ Vacuum: 6mm tubing min 0.6 bar

Options

- ◆ Process chemical heating
- ◆ Numerous spray nozzles
- ◆ Low contact or vacuum chucks
- ◆ USB and Ethernet
- ◆ Position recording
- ◆ External media cabinet with exhaust connection
- ◆ Multiple drain switching
- ◆ PC Laptop control
- ◆ Customized options are possible
- ◆ Standard or individual substrate-chuck



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